

PATENT

Docket No.: 29273/516

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANTS : Shigeo MORIYAMA et al.
SERIAL NO. : (Unassigned)
FILED : (Herewith)
FOR : POLISHING APPARATUS AND METHOD FOR
PRODUCING SEMICONDUCTORS USING THE
APPARATUS
GROUP ART UNIT : (Unassigned)
EXAMINER : (Unassigned)

ASSISTANT COMMISSIONER
FOR PATENTS
Washington, D.C. 20231

**INFORMATION DISCLOSURE STATEMENT
UNDER 37 C.F.R. § 1.97 & § 1.98**

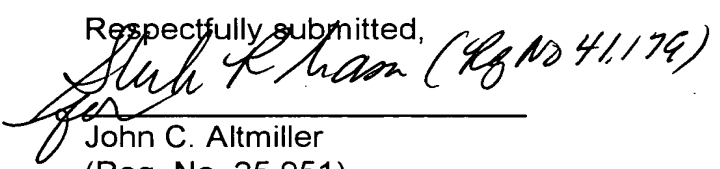
S I R:

In conformance with Applicants' duty of disclosure under 37 C.F.R. § 1.56 (a) and § 1.97(b)(1), the references listed on the attached form PTO-1449 are hereby brought to the Examiner's attention.

In compliance with 37 CFR 1.98, copies of the references are is submitted herewith.

It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear in the "references cited" on any patent to issue therefrom.

Respectfully submitted,

Date: 18 January 2000
John C. Altmiller
(Reg. No. 25,951)

KENYON & KENYON
1500 K Street, NW, Suite 700
Washington, D.C. 20005

Tel. (202) 220-4200
Fax. (202) 220-4201
315849